

iMiD 2024

The 24th International Meeting on Information Display
August 20-23, 2024 / ICC Jeju, Jeju, Korea

Session Title:	01. Metrology and Inspection for Micro Display
Session Date:	August 21 (Wed.), 2024
Session Time:	09:00-10:30
Session Room:	Room A (Halla A)
Chair(s):	Prof. Tae-gon Kim (Hanyang Univ., Korea) Dr. Yong Jun Park (Samsung Display Co., Ltd., Korea)

[A01-1] [Invited] 09:00-09:25

Latest Methods of Measuring Virtual Reality Device Displays

Eric Eisenberg (Radiant Vision Systems, USA)

[A01-2] [Invited] 09:25-09:50

Photoluminescence-Based Optical Inspection Metrologies for GaN / InGaN μ LED Wafers

Sami Dzsaber, Adam Virovecz, Zsolt Szekrényes, and György Nádudvari (SEMILAB Co., Ltd., Hungary)

[A01-3] [Invited] 09:50-10:15

Emerging Trends in MicroLED Chip Architecture, Metrology, and Inspection

David Lewis (InZiv Ltd., Israel)

[A01-4] 10:15-10:30

Machine Learning and Deep Learning Based Display Defect Detection and Classification Strategy

Sanghoon Cho, Myeongho Song, Changhyun Park, and Sangrak Son (Samsung Display Co., Ltd., Korea)